



DBs: USPAT, EPO, IPO, DERVENT, IBM, TDB

Plurals

Default operator: OR Highlight all hit terms initially

6 and interlayer adj dielectric

DBS1 Text HTML

U	I	Document ID	Issue Date	Pages	Title	Current OR	Current XRef
1	<input checked="" type="checkbox"/>	US 6624473 B1	20030923	55	Thin-film transistor, panel, and methods for producing them	257/344	257/401; 257/408;
2	<input checked="" type="checkbox"/>	US 6614052 B1	20030902	28	Semiconductor display devices and applications	257/59	257/350; 257/351;
3	<input checked="" type="checkbox"/>	US 6589824 B2	20030708	27	Process for fabricating semiconductor device	438/151	257/E21.134; 257/E21.413;
4	<input checked="" type="checkbox"/>	US 6541793 B2	20030401	26	Thin-film transistor and semiconductor device using thin-film transistors	257/57	257/67; 257/E21.413;
5	<input checked="" type="checkbox"/>	US 6528820 B1	20030304	21	Semiconductor device and method of fabricating same	257/66	257/347; 257/49;
6	<input checked="" type="checkbox"/>	US 6331476 B1	20011218	26	Thin film transistor and producing method thereof	438/486	257/E21.413; 257/E21.577;
7	<input checked="" type="checkbox"/>	US 6326248 B1	20011204	26	Process for fabricating semiconductor device	438/151	257/E21.134; 257/E21.413;
8	<input checked="" type="checkbox"/>	US 6323072 B1	20011127	36	Method for forming semiconductor thin film	438/166	148/DIG.1; 257/E21.133;
9	<input checked="" type="checkbox"/>	US 6310363 B1	20011030	24	Thin-film transistor and semiconductor device using thin-film transistors with N and	257/59	257/347; 257/348;
10	<input checked="" type="checkbox"/>	US 6211535 B1	20010403	15	Method of manufacturing a semiconductor device	257/66	257/65; 257/E21.413;